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Form 1449 (Modified)	Atty/Docket No. 49AM1P118/P0539	Application No.: 09/408,921		
Information Disclosur ADEMAR	Applicant:			
Statement By Applicant	Ricci, et al.			
	Filing Date	Group		
(Use Several Sheets if Necessary)	September 30, 1999	1763		

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Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.